# Exhibit 25



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# (12) United States Patent

Madiwal et al.

## (54) GAS SYSTEMS AND METHODS FOR CHAMBER PORTS

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U.S.C. 154(b) by 200 days.

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- (52) **U.S. CI.**CPC ....... *H01L 21/6719* (2013.01); *C23C 14/564* (2013.01); *C23C 14/566* (2013.01); (Continued)

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### (58) Field of Classification Search

CPC ............ H01L 21/6719; H01L 21/67126; C23C 16/45563; C23C 14/566; C23C 14/564; C23C 16/4401; Y10T 29/49432 See application file for complete search history.

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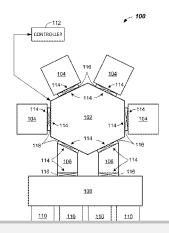
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### (57) ABSTRACT

An electronic device manufacturing system may include a chamber port assembly that provides an interface between a transfer chamber and a process chamber. In some embodiments, the chamber port assembly may be configured to direct a flow of purge gas into a substrate transfer area of the chamber port assembly. In other embodiments, a process chamber and/or the transfer chamber may be configured to direct a flow of purge gas into the substrate transfer area. The flow of purge gas into a substrate transfer area may prevent and/or reduce migration of particulate matter from chamber hardware onto a substrate being transferred between the transfer chamber and a process chamber. Methods of assembling a chamber port assembly are also provided, as are other aspects.

### 11 Claims, 12 Drawing Sheets





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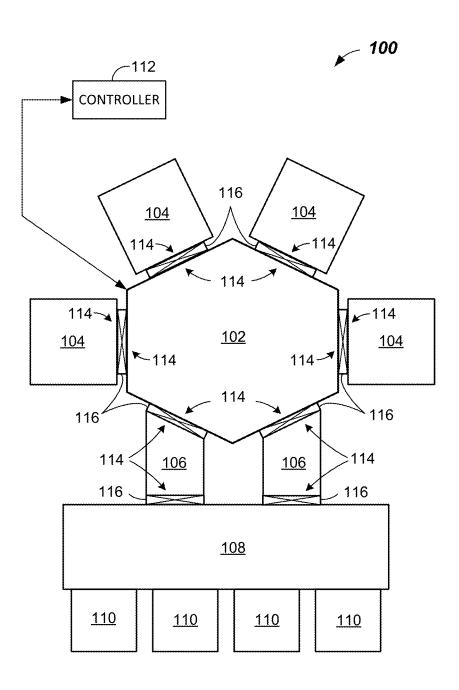


FIG. 1



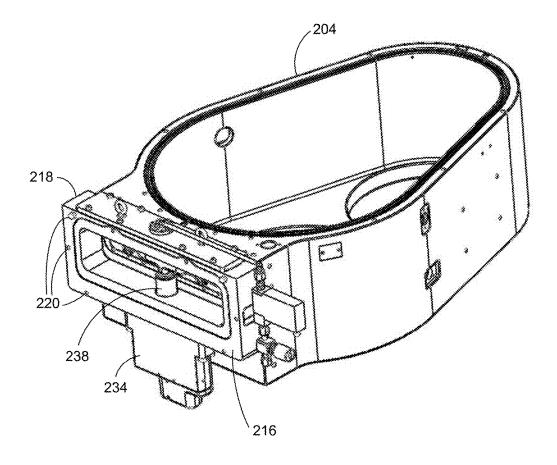


FIG. 2



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